
**Microbeam analysis — Electron
probe microanalysis — Guidelines
for qualitative point analysis
by wavelength dispersive X-ray
spectrometry**

*Analyse par microfaisceaux — Analyse par microsonde électronique
(Microsonde de Castaing) — Lignes directrices pour l'analyse
qualitative ponctuelle par spectrométrie de rayons X à dispersion de
longueur d'onde (WDX)*

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ISO copyright office
Case postale 56 • CH-1211 Geneva 20
Tel. + 41 22 749 01 11
Fax + 41 22 749 09 47
E-mail copyright@iso.org
Web www.iso.org

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Foreword

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The committee responsible for this document is ISO/TC 202, *Microbeam analysis*, Subcommittee SC 2, *Electron probe microanalysis*.

This second edition cancels and replaces the first edition (ISO 17470:2004), of which it constitutes a minor revision.

Introduction

Electron probe microanalysis is used to qualitatively identify the elements present in a specimen on a micrometric scale. It is necessary to specify the measurement conditions and identification method in order to avoid reporting erroneous or inconsistent results.

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